PATENT ABSTRACTS OF JAPAN

(11) Publication number: 2001005793 A (43) Date of publication of application; 12.01.2001

(51) Int. CI G06F 15/177 G06F 3/00

 (21) Application number:
 11178725
 (71) Applicant:
 MITSUBISHI ELECTRIC CORP

 (22) Date of filing:
 24.06.1999
 (72) Inventor:
 KANAEGAMI ATSUSHI

(54) EVENT MANAGEMENT SYSTEM

(57) Abstract:

PROBLEM TO BE SOLVED. To prevent the dependency relation between events as information which is easy for an administrator to recognize according to many pieces of event information gathered from repective nodes by providing an event relation analyzing means, a display means which graphically displays directed graph information generated by the event relation analyzing means, etc.

SOLUTION: An event gathering part 10 gathers events generated at respective nodes N to N4. Then a restriction retrieval part 12 extracts restrictions relating to event information that the event gathering part 10 gathers from a restriction database 13. Further, an event relation analysis part 11 performs an event relation analysis process. Namely, the event information gathered by the event process to a consider the event process to the event process that the event information between pieces of event information retireval part 12 are analyzed to generate directed graph information between pieces of event information. Then a relation display part 14 graphically displays a directed graph according to the directed graph information between the increase of event information are the process of event information on the directed graph according to the directed graph information between the sizes of event information on the dependency re-

lation between the pieces of event information which are needed for fault search or fault countermeasures can accurately be presented to the administrator. COPYRIGHT: (C)2001, JPO

